

INTERFEROMETRIC SYSTEM FOR
PRECISION IMAGING OF VIBRATING STRUCTURES

Abstract of the Disclosure

5 An optical profiler is modified in a way which allows it to
image a MEMS device at various points during the movement of the
MEMS device. The light source is synchronized with a desired
movement of the MEMS device. The light source produces pulse at
each synchronization period. During each pulse, an
10 interferometric measurement is carried out. So long as the pulse
is short enough such that the device does not move significantly,
a detection of the position of the device can be accurately
obtained.